

ABSTRACT

A system and method are disclosed in which a substrate includes a plurality of functional sites, wherein each site comprises a micro-device for handling microcomponent parts. For instance, in a preferred embodiment, functional sites are included on a substrate for at least performing rotational tasks. That is, in a preferred embodiment, a plurality of functional sites are included on a substrate, wherein each functional site comprises a micro-device for handling a microcomponent part presented thereto to perform rotation of the part in some manner. The plurality of micro-devices may be operable to rotate a microcomponent part about various different axes of rotation. For instance, in one embodiment, full rotational handling (rotation about all three axes of a three-dimensional coordinate system) may be provided by the micro-devices.

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